27	28	26	25	24	N ε	21	20	19	18	13	14	17	16	15	12	10	Φ α	7	<u>ი</u> თ	44 17	ωι	→	י ביינושילו
155	682	67	31	44,	127	86442	0	ь	0	37	н	0	0	0	324	, ₊	0 T3	4.0	27	Q +4	0	793	
oxide)) and semiconductor walls or spacers) near2 (layers or multilayer)) gates)) and ((silicon near2 nitride) or (silicon adi oxide)) and semiconductor	conductor spacers) near2 (layers or multilayer)) on near2 nitride) or (silicon adj	crier or prevent))) lewall near2 (layers or multilayer)) and (transistor adj (gate or gates))) and ((BPSG or PSG or BSG or ASG) and ((dopant with barrier)) cls. or 257/\$.ccls.) and (("Si.sub.x O.sub.y N.sub.z" or "SiON" or o.sub.3" or oxynitride or (aluminum adj oxide)) same (spacer and ((BPSG or PSG or BSG or ASG) and ((dopant or diffusion) with	adj oxide)) same (spacer O.sub.y N.sub.z" or "SiON" or adj oxide)) same (spacer	e (spacer	(("A; Air A O Air A N Air A" OT "A'ON" OT HITCELOR!	uminum adj oxide)) and BPSG and (silicon nitride) and (dopant adj barrier) miconductor) and substrate and transistor and ((oxynitride) or (aluminum	(dopant adj barrier) on adj oxynitride) or	xide)) and BPSG and (silicon nitride) and substrate and transistor and ((silicon adj oxynitride) or	<pre>xide)) and BPSG and (silicon nitride) and substrate and transistor and ((silicon adj oxynitride) or</pre>)) and BPSG and (silicon nitride) substrate and transistor and ((silicon adj oxynitride) or	ilicon adj oxynitride) or	and (silicon nitride) and transistor and ((silicon adj oxynitride) or	oxynitride) or	ilicon adj oxynitride) or	99") or ("438/301")).CCLS.) and (dopant adj barrier)	"5700349" and (dopant adj barrier)	or ("5250472") or ("5308793") or ("5573633")).PN.	((("438/299") or ("438/301")).CCLS.) and (aluminum adj oxide)	or ("438/301")).CCLS.) and (siliconoxynitride)	or ("438/301")).CCLS.) and (SixOyNz)	(("438/299") or ("438/301")).CCLS	(000) - (1100 (101) COT O
USPAT	USPAT	USPAT	USPAT	USPAT	USPAT	USPAT	JPO	USPAT	US-PGPUB	US - PGPUB	EPO	IBM TDB	DERWENT	JPO	USPAT	USPAT	USPAT	USPAT	USPAT	USPAT	USPAT	USPAT	יייי
2002/01/25 16:35	2002/01/25 16:35	2002/01/25 16:31	2002/01/25 16:22		2002/01/25 16:12	2002/01/25 16:07	2002/01/25 16:06	2002/01/25 15:50	2002/01/25 15:50	2002/01/25 15:49	2002/01/25 15:45	2002/01/25 15:42	2002/01/25 15:42	2002/01/25 16:06	2002/01/25 15:4		2002/01/25 14:		2002/01/25 14			2002/01/25 14:15	101/10

31	30	29
7	413	632
Ď	oxynitride) or (aluminum adj oxide)) and semiconductor and (438/\$.ccls. or 257/\$.ccls.) (((sidewall or spacer or sidewalls or spacers) near2 (layers or multilayer)) and (transistor or gate) and ((silicon near2 nitride) or (silicon adj	ayer))
USPAT	USPAT	USPAT
2002/01/25 16:40	2002/01/25 16:38	2002/01/25 16:35
	oxynitride) or (aluminum adj oxide)) and semiconductor and (438/\$.CCIs. or 257/\$.ccls.)) and ((sidewall or spacer or sidewalls or spacers) same ((silicon adj oxynitride))) adj oxynitride) or (aluminum adj oxide) or (silicon adj nitride)) disconsition or spacers) near2 (layers or multilayer)) USPAT	oxynitride) or (aluminum adj oxide)) and semiconductor and (438/\$.ccls. or (sidewall or spacer or sidewalls or spacers) near2 (layers or multilayer)) 413 (((sidewall or spacer or sidewalls or spacers) near2 nitride) or (silicon adj oxynitride) or (aluminum adj oxide)) and semiconductor and (438/\$.ccls. or oxynitride) or (aluminum adj oxide) or sidewalls or spacers) same ((silicon adj oxide)) adj oxynitride) or (aluminum adj oxide) or (silicon adj nitride)) 7 (((sidewall or spacer or sidewalls or spacers) near2 (layers or multilayer)) USPAT